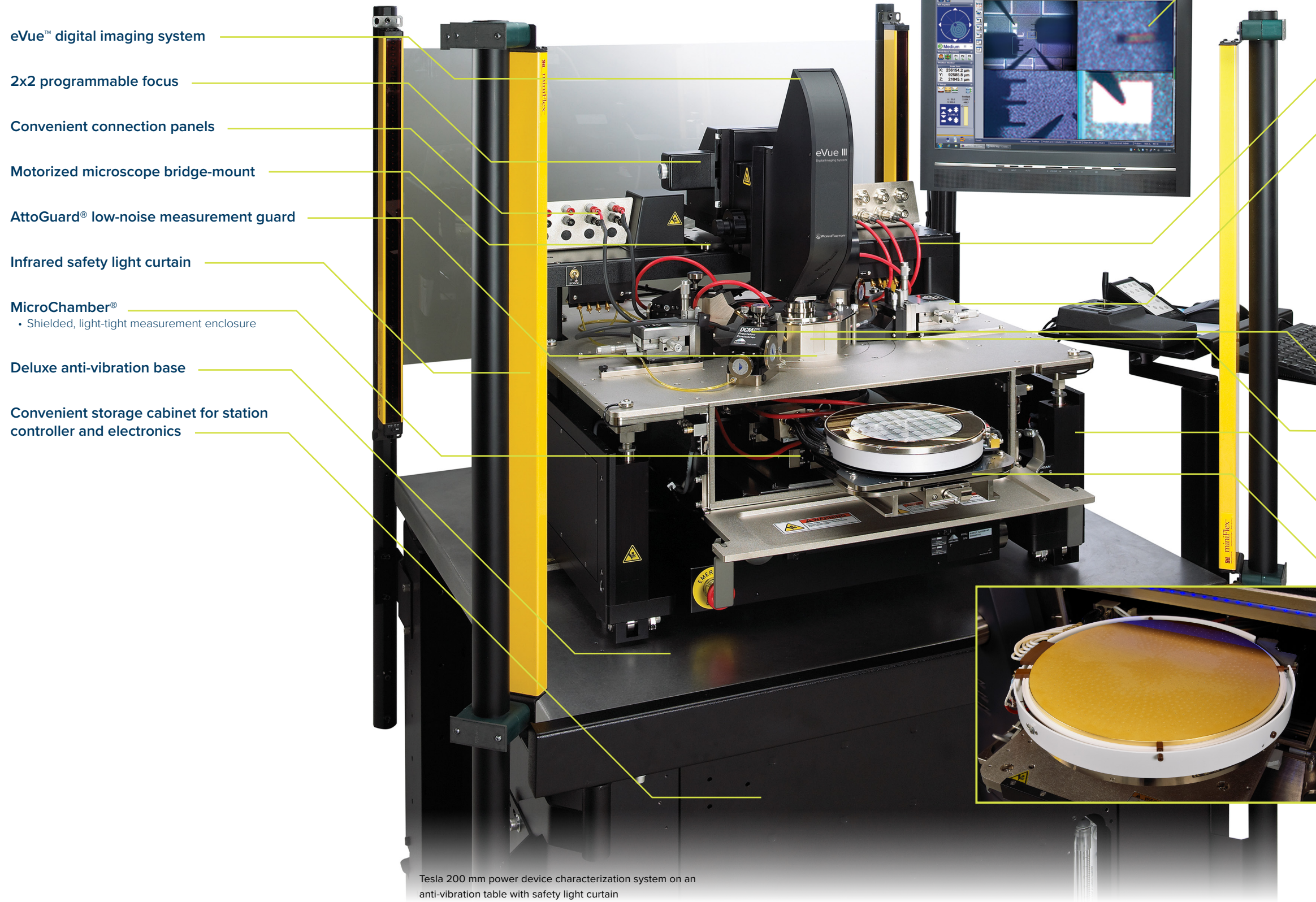


# Cascade Tesla

High-voltage/High-current Measurements for Today's High-performance Power Devices



eVue™ digital imaging system

2x2 programmable focus

Convenient connection panels

Motorized microscope bridge-mount

AttoGuard® low-noise measurement guard

Infrared safety light curtain

MicroChamber®  
• Shielded, light-tight measurement enclosure

Deluxe anti-vibration base

Convenient storage cabinet for station controller and electronics

## Powerful automation tools for data collection

- Automatic wafer alignment
- Auto XYZ and theta correction for sub-micron stepping
- Automatic die size measurement tool

## Velox™ probe station control software

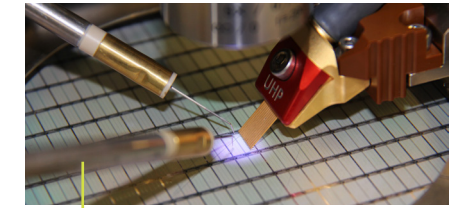
- Intuitive GUI for efficient system utilization by novice and expert users
- Software joystick for precise, sub-micron positioning
- Improved sub-die navigation with CellView
- Easy integration with instrument, testers, and test and measurement software for fast data collection

## High-voltage cable

- Supports up to 10,000 V

## UHP probe micropositioner

- Holds one UHP high-current parametric probe holder
- Supports up to 300 A (pulsed) /20 A (DC)
- Can be combined as parallel configuration to support 600 A



## HVP high-voltage parametric probe holder with replaceable probe tips

- Supports up to 10,000 V

## HVP probe micropositioner

## TopHat™ enclosure

- Light-tight
- Extends the MicroChamber shield to the probe

## 200 mm manual/semi-automated or 300 mm semi-automated probe station

- 3,000 V (triaxial) /10,000 V (coaxial), 600 A
- Low-noise performance package

## Safely load and unload wafers

- Full wafer access via locking roll-out stage

## Gold-plated high-power chuck

- Minimal chuck-to-wafer contact resistance
- Thin-wafer mounting
- Max 600 A current handling capability
- Low leakage
- -55°C to 300°C
- Supports up to 10,000 V

Tesla 200 mm power device characterization system on an anti-vibration table with safety light curtain